



## Wir schaffen Wissen – heute für morgen

## Paul Scherrer Institut Jörg Raabe

How to Find Samples: Precise Positioning and Complementary Microscopy Techniques

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- Challenges
- Sample positioning
- Focusing
- Finding samples







- Mechanical Stability, 100Hz -> 10ms positioning time high resonance frequencies necessary
- Thermal stability:

1°C temperature change result in 1µm length change for 10cm of typical construction material



- PolLux: Scanning transmission x-ray microscopy (STXM)
- OMNY: Test setup & Design of UHV/Cryo Version







# **OMNY Test Setup**





**OMNY Test Setup** 

Limited to atmospheric pressure and room temperature



Position of sample to optics measured by laser interferometry and actively stabilized

Position stability routinely reached: 8 nm (stdev) horizontally, 3 nm (stdev) vertically

ightarrow high resolution imaging should be possible

Further information can be found in Mirko Holler, Joerg Raabe, Ana Diaz, Manuel Guizar-Sicairos, Christoph Quitmann, Andreas Menzel, and Oliver Bunk, "An Instrument for 3D X-ray Nano-Imaging", Review of Scientific Instruments, accepted for publication.



# **OMNY Test Setup – 2D imaging**

2D lithographic test object:

concentric circles of hydrogen silsesquioxane HSQ, at two height levels subsequently coated with a conformal layer of iridium of about 17 nm in thickness by atomic layer deposition.



Phase of the reconstructed test structures (radians) at a field of view of  $3x3 \ \mu m^2$ , reconstructed to 6 nm pixel size FZP illumination, X-ray beam Ø 2  $\mu m$ 



Thanks to Joan Vila-Comamala for sample preparation at LMN, PSI















# **Metrology for OMNY**

For high resolution imaging accurate information on the position of the sample in respect to the beam required i.e. the relative position of the sample to the Fresnel zone plate

#### Required:

- sub-nm resolution at high bandwidth
- exteroceptive: include thermal drifts in the measurement





#### Heterodyne laser interferometry

- Resolution: 0.3 nm
- Noise: 2 nm (stdev)
- non-contact, long range
- linear scale



# **Metrology for OMNY: Tracking interferometer**

Wobble motion is detected by laser beam deflection with

a position sensitive detector (PSD)

Closed loop: interferometer tracks the reference sphere

and keeps pointing a its center

 $\rightarrow$  interferometer data at all rotation angles







### pat. pend.





• Refractive optics





# Ex situ:

Measuring Positions of particles with respect to reference

marks



### In situ:

Integrate complementary microscope into the endstation:

- TEM
- SEM
- Visible + x-ray microscope







## **Objective lens of a TEM**







http://www.microscopy.ethz.ch







Omicron: Modified Zeiss Gemini







http://www.tescan.com





- Stable and precise positioning System with exteroceptive metrology system
- Complementary in situ microscopy
- Cryo sample transfer



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